



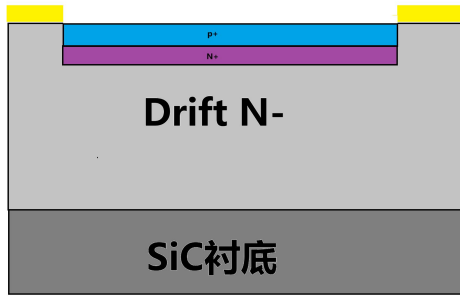
离子注入法，保护环终端



热氧化+钝化层100nm



刻蚀钝化层



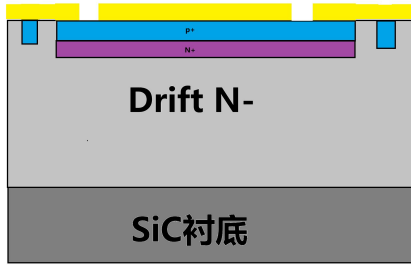
离子注入



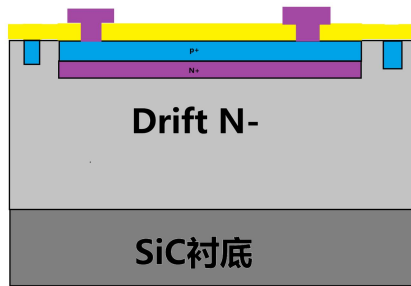
再氧化, 刻蚀



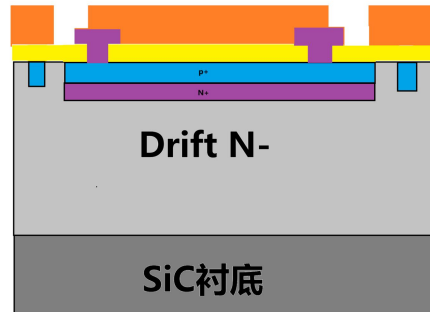
保护环



氧化刻蚀



欧姆电极

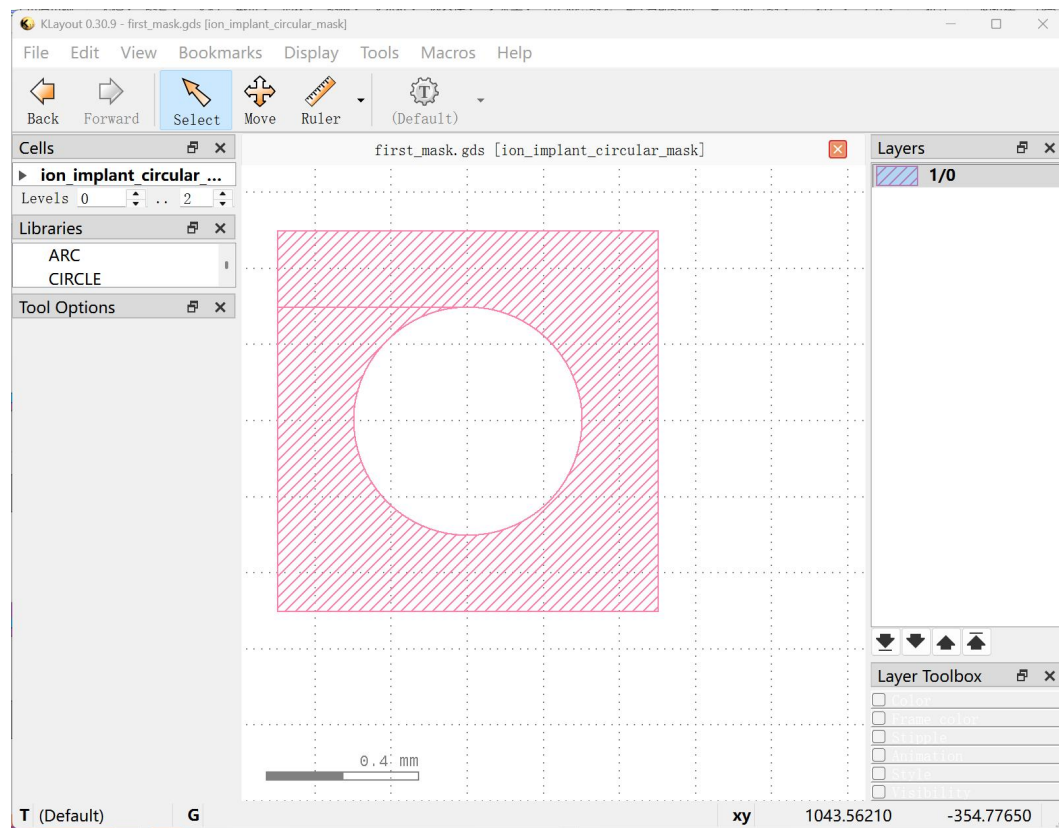


氧化刻蚀



加场板

2 离子注入光刻板



保护环光刻板

